

The attached Appendix includes marked-up copies of each rewritten paragraph  
(37 C.F.R. §1.121(b)(1)(iii)) and claim (37 C.F.R. §1.121(c)(1)(ii)).

Respectfully submitted,



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Attachment:  
Appendix

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## APPENDIX

## Changes to Specification:

Page 2, lines 4-9:

In Japanese Patent Application Laid-Open No. H11-5807458704, however, compensation data must be produced for each nozzle, an operation which involves time and trouble. Also, because it is necessary to provide drive voltage control means separately for each nozzle, the circuit configuration must of necessity be made complex.

## Changes to Claims:

The following are marked-up versions of the amended claims:

5. (Amended) The ink jet recording apparatus according to ~~any one of~~ claims 1-~~to~~4, wherein positions on ink jet head on which said plurality of nozzles is arranged are divided into a plurality of areas, and nozzles belonging to each area are made to belong to a single group.

6. (Amended) The ink jet recording apparatus according to ~~any one of~~ claims 1-~~to~~5,

wherein said ink jet head on which said plurality of nozzles is arranged comprises cavities provided for each of said nozzles, a reservoir communicating to said cavities and common to said nozzles, and a supply port for supplying said functional liquid to said reservoir; and

wherein said plurality of groups comprise at least a first group comprising nozzles of said plurality of nozzles positioned close to said supply port, and a second group comprising nozzles of said plurality of nozzles positioned far from said supply port.

9. (Amended) The method for manufacturing a functional liquid applied substrate according to claim 7-~~or~~8,

wherein said ink jet head on which said plurality of nozzles is arranged comprises cavities provided for each of said nozzles, a reservoir communicating to said cavities and common to said nozzles, and a supply port for supplying said functional liquid to said reservoir; and

wherein said plurality of groups comprise at least a first group comprising nozzles of said plurality of nozzles positioned close to said supply port, and a second group comprising nozzles of said plurality of nozzles positioned far from said supply port.

10. (Amended) A method for manufacturing a device comprising a functional liquid applied substrate manufactured by the method according to ~~any one of claims 7 to 9~~.

12. (Amended) A device comprising a functional liquid applied substrate manufactured by the method according to ~~any one of claims 7 to 9~~.

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